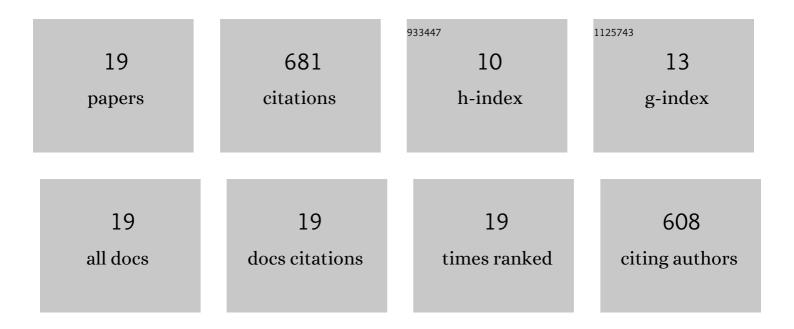
## Eldwin J Ng

List of Publications by Year in descending order

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**FLOWIN LNC** 

#	Article	IF	CITATIONS
1	Micro-Tethering for Fabrication of Encapsulated Inertial Sensors With High Sensitivity. Journal of Microelectromechanical Systems, 2019, 28, 372-381.	2.5	7
2	Direct Detection of Akhiezer Damping in a Silicon MEMS Resonator. Scientific Reports, 2019, 9, 2244.	3.3	48
3	A Unified Epi-Seal Process for Fabrication of High-Stability Microelectromechanical Devices. Journal of Microelectromechanical Systems, 2016, 25, 489-497.	2.5	107
4	Experimental Investigation Into Stiction Forces and Dynamic Mechanical Anti-Stiction Solutions in Ultra-Clean Encapsulated MEMS Devices. Journal of Microelectromechanical Systems, 2016, 25, 469-478.	2.5	22
5	Nonlinearity of Degenerately Doped Bulk-Mode Silicon MEMS Resonators. Journal of Microelectromechanical Systems, 2016, 25, 859-869.	2.5	41
6	Autonomous calibration of MEMS disk resonating gyroscope for improved sensor performance. , 2016, , $\cdot$		5
7	Stable Encapsulated Charge-Biased Resonators. Journal of Microelectromechanical Systems, 2016, 25, 30-37.	2.5	3
8	Tunable quality factor through 1:1 modal coupling in a disk resonator. , 2015, , .		6
9	A unified epi-seal process for resonators and inertial sensors. , 2015, , .		8
10	Temperature Dependence of the Elastic Constants of Doped Silicon. Journal of Microelectromechanical Systems, 2015, 24, 730-741.	2.5	109
11	Erratum to "Temperature Dependence of the Elastic Constants of Doped Silicon―[Jun 15 730-741]. Journal of Microelectromechanical Systems, 2015, 24, 2178-2178.	2.5	О
12	Investigation of a Vacuum Encapsulated Si-to-Si Contact Microswitch Operated From â^'60 °C to 400 °C. Journal of Microelectromechanical Systems, 2015, 24, 1906-1915.	2.5	8
13	Mode-Matching of Wineglass Mode Disk Resonator Gyroscope in (100) Single Crystal Silicon. Journal of Microelectromechanical Systems, 2015, 24, 343-350.	2.5	102
14	Fatigue Experiments on Single Crystal Silicon in an Oxygen-Free Environment. Journal of Microelectromechanical Systems, 2015, 24, 351-359.	2.5	129
15	Characterization of Oxide-Coated Polysilicon Disk Resonator Gyroscope Within a Wafer-Scale Encapsulation Process. Journal of Microelectromechanical Systems, 2015, 24, 1687-1694.	2.5	17
16	Characterization of stiction forces in ultra-clean encapsulated MEMS devices. , 2014, , .		9
17	Fabrication and Characterization of a Vacuum Encapsulated Curved Beam Switch for Harsh Environment Application. Journal of Microelectromechanical Systems, 2014, 23, 1121-1130.	2.5	16
18	Stability of Silicon Microelectromechanical Systems Resonant Thermometers. IEEE Sensors Journal, 2013, 13, 987-993.	4.7	36

#	Article	IF	CITATIONS
19	Stability measurements of silicon MEMS resonant thermometers. , 2011, , .		8